

Amendments to the Specification:

Please replace the paragraph beginning at page 31, line 10 with the following rewritten paragraph:

--Next, in response to the result of the comparison, a decision is made in block 178. If the performance is deemed to be adequate, a second performance characteristic chosen from the impedance characteristics as illustrated in block 152, the current-voltage characteristics as illustrated in block 154, and the heating/cooling characteristics as illustrated in block 158 can be assessed. Alternatively, as illustrated in block 162, the electrostatic chuck can be installed into a vacuum chamber of a semiconductor processing system in a production line. If the performance is deemed to be inadequate, the electrostatic chuck is not installed into the vacuum chamber of the semiconductor processing system in the production line as illustrated in block 164. A decision is then made in block 166 which results in the chuck either being discarded, as illustrated in block 168, or having the failure identified. If the failure is not identifiable, the electrostatic chuck may be discarded in block 168. If the failure is identifiable and repair is appropriate, the electrostatic chuck may be replaced and/or refurbished, as illustrated in block 170, and reinstalled, as illustrated in block 171, into the vacuum chamber of the semiconductor processing system dedicated to performance analysis, and the analysis routine is reiterated.--